

Title (en)

Micromechanical device and process for its manufacture

Title (de)

Mikromechanisches Bauelement und entsprechendes Herstellungsverfahren

Title (fr)

Dispositif micromécanique et son procédé de fabrication

Publication

**EP 1227060 A3 20041229 (DE)**

Application

**EP 01123641 A 20011002**

Priority

DE 10103399 A 20010126

Abstract (en)

[origin: EP1227060A2] The micromechanical component has a substrate in which at least two current channels (10, 10') are provided. The channels have a common input (5) and then branch out separately. The input has a branching with a peak (P) where the inner walls of the channels separate. A first electrode (20) is provided to apply a first electric potential to the inner walls of the channels. A second electrode (30) applies a second electric potential to the outer walls of the channels. The channels may then recombine to have a common output. Independent claims also cover a method of manufacturing the components by etching.

IPC 1-7

**B81B 1/00**; **F04B 19/00**

IPC 8 full level

**B81B 1/00** (2006.01); **F04B 17/00** (2006.01); **F04B 19/00** (2006.01)

CPC (source: EP)

**F04B 17/00** (2013.01); **F04B 19/006** (2013.01)

Citation (search report)

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Designated contracting state (EPC)

AT BE CH CY DE DK ES FI FR GB GR IE IT LI LU MC NL PT SE TR

DOCDB simple family (publication)

**EP 1227060 A2 20020731**; **EP 1227060 A3 20041229**; **EP 1227060 B1 20141210**; DE 10103399 A1 20020822

DOCDB simple family (application)

**EP 01123641 A 20011002**; DE 10103399 A 20010126